

High Performance Mass Flow Controller

SEC-Z500X





*Introducing the remarkable x ,
a break-through in mass flow control technology*

The mass flow controller, is a key piece of semiconductor manufacturing equipment. Its quality and efficiency play a major role in the success or failure of the semiconductor manufacturing process. HORIBA STEC, a company that has consistently introduced high-quality, highly functional products to the demanding semiconductor manufacturing market, and thereby grown its worldwide market share to over 30%*¹, has recently developed a new mass flow controller, one that breaks the mold completely and will change the future of mass flow control technology.

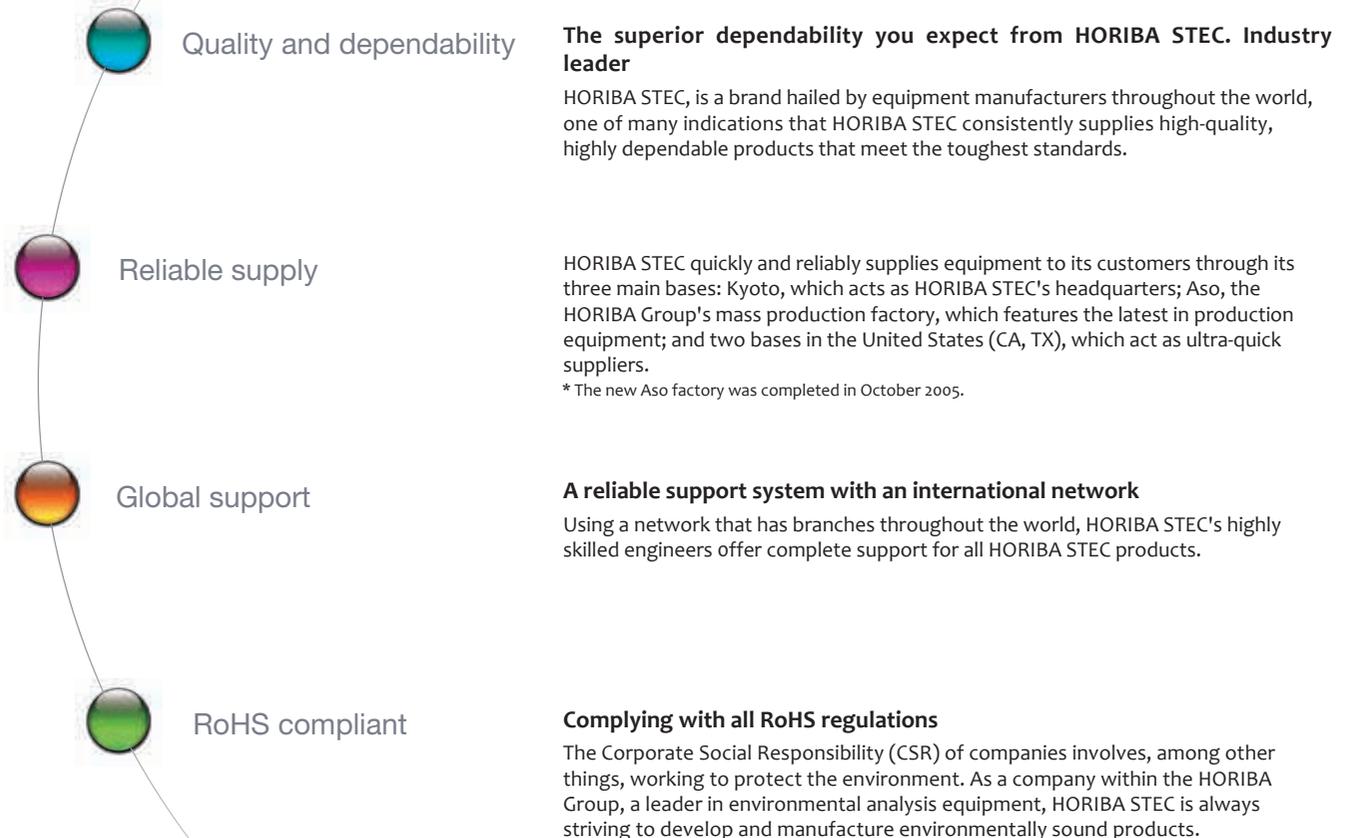
That new mass flow controller is the SEC-Z500X. It provides all the mass flow functions customers need, including the flexibility to handle different gas types and flow volumes.

The customer him or herself can alter its specifications to suit changing needs*². The unit is also RoHS compliant, which makes it the perfect environmentally friendly tool for improving corporate value.

The highly functional, high added value 'X' is brimming with previously unknown charm. The world is witnessing the birth of a mass flow controller that will change the future of the semiconductor industry.

SEC-Z500X, revealed for the first time

*¹ From HORIBA STEC's 2012 research.
*² Multi-gas, multi-range function



RoHS regulations:
 RoHS stands for "Restriction of Hazardous Substances" and is a set of regulations enforced in the EU to limit the use of six hazardous substances (lead, mercury, cadmium, hexavalent chromium, polybrominated biphenyls (PBBs) and polybrominated diphenyls ether (PBDE)), in electric and electronic components.

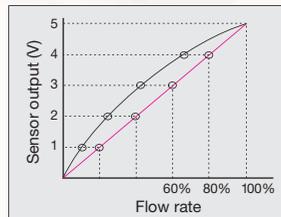


High accuracy

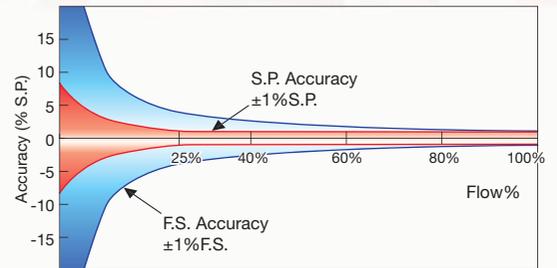
High accuracy ±1.0% S.P.

MFC's linearity is compensated by polynomial approximated curve. This achieves high accuracy for all flow control ranges. For the purpose of advancement of actual gas accuracy, the calibration data of various process gases are measured by HORIBA STEC standard gas measurement system.

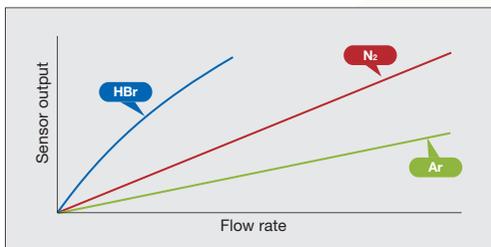
Accuracy	±1.0% S.P.	: 25–100% F.S.
	±0.25% F.S.	: ≤25% F.S.



$$y = ax^5 + bx^4 + cx^3 + dx^2 + ex + f$$



Gas flow rate characteristic curve



Gases used in semiconductor processes have a variety of different properties. The flow rate calibration function used in the SEC-Z500X series uses detailed measurement data about the flow rate characteristics of each type of process gas, across different flow rate ranges, as a basis for calibration. This huge store of measurement data paired with highly reliable sensors and the latest in calibration technology ensures extremely precise process gas flow rate control.

Traceability

The National Institute of Standards and Technology (NIST, a U.S. organization) certifies the traceability of the flow rate calibration used by the SEC-Z500X series. These units use a flow rate calibration unit that meets NIST calibration standards.



High-precision standard flow rate system

The latest high-precision standard flow rate system is installed at HORIBA STEC's bases in the United States and Japan. This system, which uses a build-up method, can measure the flow rate of process gases, including those containing a high level of toxic substances, and volatile gases. The measured data is centrally managed through a database maintained at headquarters, which allows HORIBA STEC to continually improve process gas flow rate control precision.





We never compromise on performance.

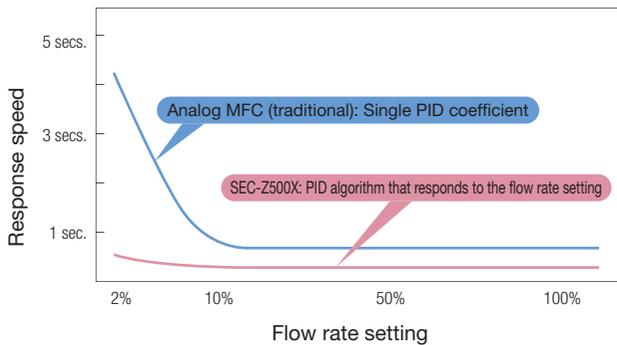


High-speed response throughout the flow rate range

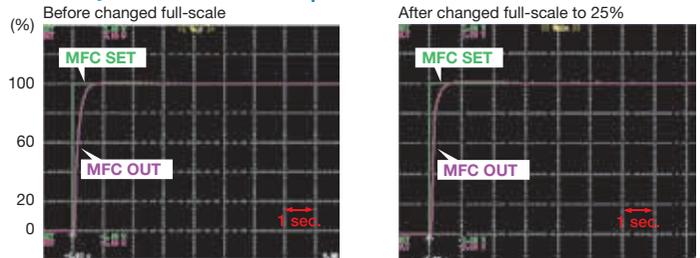
High speed response

SEC-Z500X is installed with a newly developed "Variable PID system", which can achieve 1 second response to all setting points. Variable PID is continuously changing depending on setting flow points. This allows the PID factor to be optimized when you change full scale flow and gase.

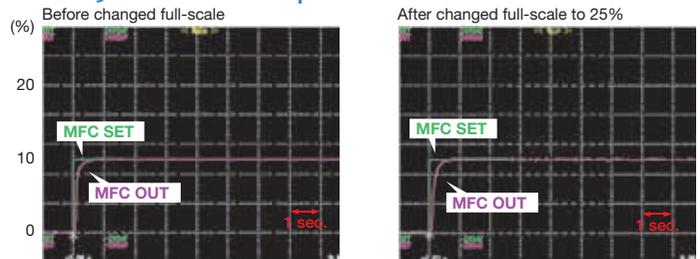
Response speed comparison, with and without the PID algorithm



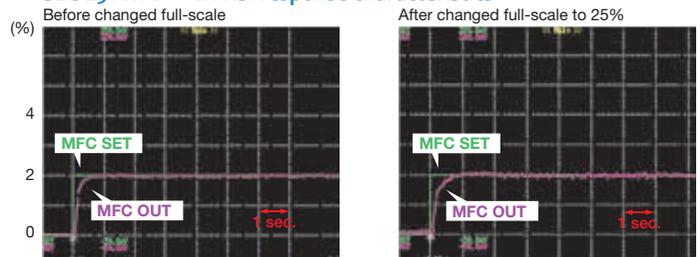
SEC-Z500X → 100% F.S. response characteristics



SEC-Z500X → 10% F.S. response characteristics



SEC-Z500X → 2% F.S. response characteristics



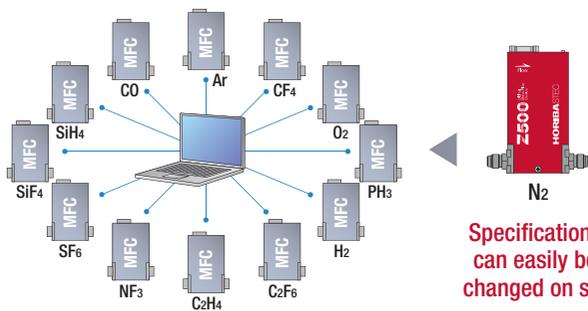


The best in quality for you



Multi-gas, multi-range solution

HORIBA STEC has made it possible for the user to change the type of gas or full-scale flow rate on site. Our special Z500 configuration software makes it possible to change these specifications at will. Best of all, the changes can be made without removing the mass flow controller from the gas panel or piping. This reduces the number of spare mass flow controllers users need to store, and helps save both time and money.



Suitable for multiple types of gas

Freely change types of gas



Suitable for multiple ranges

Freely change the full scale



Changing the full-scale flow rate

Even when the same full-scale values are used, the MR/MG numbers associated with the full-scale flow rate values for the calibration gas may vary, due to variations in the thermal conductivity of the different process gases. To increase flow rate calibration precision, HORIBA STEC offers the following lineup of MR/MG numbers.

List of full-scale flow rates for different gases

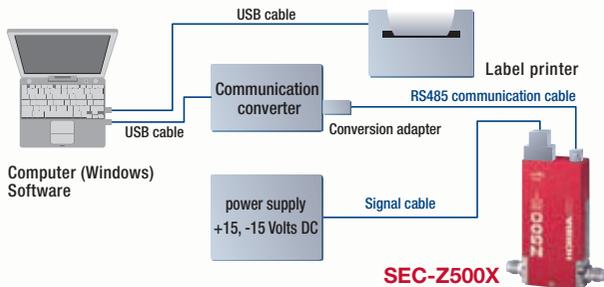
Gas type MR/MG number	N ₂	Ar	H ₂	SF ₆	HBr	WF ₆
SEC-Z51_X series						
R01	3 - 10	4 - 11	3 - 10	1 - 3	—	—
R1.5	/	/	/	/	—	—
01	8 - 30	11 - 35	8 - 30	3 - 11	5 - 9	—
1.5	/	/	/	/	9 - 17	—
02	25 - 100	35 - 110	25 - 100	9 - 36	15 - 28	5 - 6
2.5	/	/	/	/	25 - 50	6 - 11
03	75 - 300	110 - 350	75 - 300	28 - 100	44 - 86	11 - 20
3.5	/	/	/	/	79 - 150	19 - 37
04	250 - 1000	350 - 1100	250 - 1000	90 - 350	150 - 280	34 - 67
4.5	/	/	/	/	280 - 540	60 - 110
05	750 - 3000	1100 - 3500	750 - 3000	260 - 1000	470 - 930	110 - 200
5.5	/	/	/	/	910 - 1800	200 - 380
06	2500 - 10000	3500 - 11000	2500 - 10000	780 - 3100	1700 - 3300	360 - 700
SEC-Z52_X series						
6.5	/	/	/	/	2800 - 9000	—
07	10000 - 30000	10000 - 30000	10000 - 30000	2700 - 7800	9000 - 17000	—
08	30000 - 50000	30000 - 50000	30000 - 50000	7800 - 13000	15000 - 29000	—

Minimum flow rate — maximum flow rate
Unit : SCCM



Configuration software that allows the user to alter specifications on-site

The SEC-Z500X offers multi-gas, multi-range functionality, thanks to its configuration software. This software makes it possible to select MR/MG numbers simply by entering the type of gas being used and the flow rate range, and also features a handy N₂ gas conversion feature for flow rate measurements using N₂ gas during receipt inspections. To ensure that the software is used without error, HORIBA STEC offers software operation trainings. For information on these trainings, please contact your HORIBA STEC representative.



Name	Notes
Computer	OS: Japanese or English, Windows® 2000 / XP / Vista / 7 / 8
Software	Configuration software HORIBA STEC offers trainings detailing the use of the software.
Communications converter (serial)	RS-485 Please consult your HORIBA STEC representative for further information
Conversion adapter	Dedicated adapter CA-EDP9RJ45
RS485 communication cable	Dedicated cable SC-EBR
USB cable	Cable for label printer and communication converter
Label printer	Please consult your HORIBA STEC representative for further information

The customer can supply all the system components listed above, if desired, except for the software, which must be provided by HORIBA STEC. Please consult your HORIBA STEC representative for more detailed specifications.

Product specifications

Digital/Analog communication models

Mass flow controller model	*1	SEC-Z512KX	SEC-Z512MGX	SEC-Z522MGXN	SEC-Z522MGX	
Mass flow meter model	*1	SEF-Z512KX	SEF-Z512MGX	SEF-Z522MGXN	SEF-Z522MGX	
Full-scale flow rate (N ₂ conversion flow rate)		1/2 SCCM	MR/MG number #R01: 10 SCCM #R1.5: 17.5 SCCM #01: 30 SCCM #1.5: 55 SCCM #02: 100 SCCM #2.5: 175 SCCM #03: 300 SCCM #3.5: 550 SCCM #04: 1 SLM #4.5: 1.75 SLM #05: 3 SLM #5.5: 5.5 SLM #06: 10 SLM		MR/MG number #6.5: 22 SLM #07: 30 SLM #08: 50 SLM	
Valve Type		O: Normally open C: Normally close				
Flow rate at fully closed control valve		≤ 2% F.S.				
Flow rate control range		2-100% of F.S.				
Flow rate measuring range (SEF)		0-100% of F.S.				
Accuracy	*2	±1.0% F.S.	±1.0% S.P. (Flow rate > 25% F.S.) ±0.25% F.S. (Flow rate ≤ 25% F.S.)			
Operating temperature		5 to 50°C (recommended temperature range: 15 to 45°C)				
Response		≤ 1 second: over full flow rate range				
Linearity		≤ ±0.5% F.S.				
Repeatability		≤ ±0.2% F.S.				
Operating differential pressure		50 to 300 kPa (d)	50 to 300 kPa (d) #5.5, #06: 100 to 300 kPa (d)		200 to 300 kPa (d)	
Operating differential pressure (SEF)		≤ 300 kPa (d)				
MAX. Operating pressure		450 kPa (g)				
Pressure resistance		1000 kPa (g)				
Leak Integrity		≤ 5 x 10 ⁻¹² Pa·m ³ /s (He)				
Flow rate setting signal		0.1 to 5 V DC (2% to F.S.): input impedance 1 MΩ or higher				
Flow rate output signal		0 to 5 V DC (0% to F.S.): minimum load resistance 2 kΩ or higher				
Digital interface		With address function: RS-485 (transmission speed 38,400 bps) F-Net Protocol				
Wetted materials		316L Stainless Steel (polished surface)				
Power supply		+15 V ±5% 150 mA -15 V ±5% 150 mA				
Signal response		Analog: D-Sub 9-pin (TOP) Digital: 2 LAN jacks (TOP)				
Standard Fitting	*3	1/4 inch VCR equivalent Option: 1.125 inch IGS, 1.5 inch IGS		1/4 inch VCR equivalent Option: 1.125 inch IGS	1.5 inch IGS	
Mounting orientation		Free				

*1 The gas type and full scale settings for the SEC(SEF)-Z512MGX, Z522MGX, Z522MGXN, Z532MGX, Z542MGX, Z552MGX and Z562MGX can be changed by the operator, using special software.

*2 The precision is that associated with the full-scale MR and MG number values. The flow rate precision guaranteed temperatures conform to SEMI standards. For details, please contact HORIBA STEC.

*3 IGS: Integrated Gas System

● SCCM and SLM are notations indicating the gas flow rate (mL/min, L/min, at 0°C and 101.3 kPa).

DeviceNet™ communication models



Mass flow controller model	*1	SEC-Z514KX	SEC-Z514MGX	SEC-Z524MGXN	SEC-Z524MGX	
Mass flow meter model	*1	SEF-Z514KX	SEF-Z514MGX	SEF-Z524MGXN	SEF-Z524MGX	
Full-scale flow rate (N ₂ conversion flow rate)		1/2 SCCM	MR/MG number #R01: 10 SCCM #R1.5: 17.5 SCCM #01: 30 SCCM #1.5: 55 SCCM #02: 100 SCCM #2.5: 175 SCCM #03: 300 SCCM #3.5: 550 SCCM #04: 1 SLM #4.5: 1.75 SLM #05: 3 SLM #5.5: 5.5 SLM #06: 10 SLM		MR/MG number #6.5: 22 SLM #07: 30 SLM #08: 50 SLM	
Valve Type		O: Normally open C: Normally close				
Flow rate at fully closed control valve		≤ 2% F.S.				
Flow rate control range		2-100% of F.S.				
Flow rate measuring range (SEF)		0-100% of F.S.				
Accuracy	*2	±1.0% F.S.	±1.0% S.P. (Flow rate > 25% F.S.) ±0.25% F.S. (Flow rate ≤ 25% F.S.)			
Operating temperature		5 to 50°C (recommended temperature range: 15 to 45°C)				
Response		≤ 1 second: over full flow rate range				
Linearity		≤ ±0.5% F.S.				
Repeatability		≤ ±0.2% F.S.				
Operating differential pressure		50 to 300 kPa (d)	50 to 300 kPa (d) #5.5, #06: 100 to 300 kPa (d)		200 to 300 kPa (d)	
Operating differential pressure (SEF)		≤ 300 kPa (d)				
MAX. Operating pressure		450 kPa(g)				
Pressure resistance		1000 kPa(g)				
Leak Integrity		≤ 5 x 10 ⁻¹² Pa·m ³ /s (He)				
Digital interface		DeviceNet™ Protocol				
Wetted materials		316L Stainless Steel (polished surface)				
Power supply		Conforming to ODVA standards, DC 24 V, 4.0 VA				
Standard Fitting	*3	1/4 inch VCR equivalent Option: 1.125 inch IGS, 1.5 inch IGS		1/4 inch VCR equivalent Option: 1.125 inch IGS	1.5 inch IGS	
Mounting orientation		Free				

*1 The gas type and full scale settings for the SEC(SEF)-Z514MGX, Z524MGX, Z524MGXN, Z534MGX, Z544MGX, Z554MGX and Z564MGX can be changed by the operator, using special software.

*2 The precision is that associated with the full-scale MR and MG number values. The flow rate precision guaranteed temperatures conform to SEMI standards. For details, please contact HORIBA STEC.

*3 IGS: Integrated Gas System

● SCCM and SLM are notations indicating the gas flow rate (mL/min, L/min, at 0°C and 101.3 kPa).

SEC-Z532MGX	SEC-Z542MGX	SEC-Z552MGX	SEC-Z562MGX	Mass flow controller model	*1
SEF-Z532MGXN	SEF-Z542MGXN	SEF-Z552MGX	SEF-Z562MGX	Mass flow meter model	*1
MR/MG number #09: 100 SLM	MR/MG number #10: 200 SLM	MR/MG number #11: 300 SLM	MR/MG number #12: 500 SLM	Full-scale flow rate (N ₂ conversion flow rate)	
O: Normally open C: Normally close		C: Normally close		Valve Type	
				Flow rate at fully closed control valve	
				Flow rate control range	
				Flow rate measuring range (SEF)	
±1.0% S.P. (flow rate > 35% F.S.) ±0.35% F.S. (flow rate ≤ 35% F.S.)		±2% S.P. (flow rate > 50% F.S.) ±1% F.S. (flow rate ≤ 50% F.S.)		Accuracy	*2
5 to 50°C (recommended temperature range: 15 to 45°C)				Operating temperature	
≤ 1 second: over full flow rate range		≤ 2 second: over full flow rate range		Response	
≤ ±0.5% F.S.		±1% F.S.		Linearity	
≤ ±0.2% F.S.		±0.5% F.S.		Repeatability	
100 to 300 kPa (d)	200 to 300 kPa (d)	150 to 350 kPa (d)	250 to 350 kPa (d)	Operating differential pressure	
≤ 300 kPa (d)		≤ 300 kPa (d)		Operating differential pressure (SEF)	
450 kPa (g)				MAX. Operating pressure	
1000 kPa (g)				Pressure resistance	
≤ 5 x 10 ⁻¹² Pa·m ³ /s (He)				Leak Integrity	
0.1 to 5 V DC (2% to F.S.): input impedance 1 MΩ or higher				Flow rate setting signal	
0 to 5 V DC (0% to F.S.): minimum load resistance 2 kΩ or higher				Flow rate output signal	
With address function: RS-485 (transmission speed 38,400 bps) F-Net Protocol		With address function: RS-495 (transmission speed 38,400 bps) F-Net Protocol		Digital interface	
316L Stainless Steel (polished surface)				Wetted materials	
+15 V ±5% 150 mA -15 V ±5% 150 mA		+15 V 150 mA -15 ±5% 150 mA		Power supply	
Analog: D-Sub 9-pin (TOP) Digital: 2 LAN jacks (TOP)		Analog: D-Sub 9-pin (TOP, SIDE) Digital: 2 LAN jacks (TOP)		Signal response	
1/2 inch VCR equivalent Option: 1. 5 inch IGS		1/2 inch VCR equivalent		Standard Fitting	*3
Free				Mounting orientation	

SEC-Z534MGX	SEC-Z544MGX	SEC-Z554MGX	SEC-Z564MGX	Mass flow controller model	*1
SEF-Z534MGXN	SEF-Z544MGXN	SEF-Z554MGX	SEF-Z564MGX	Mass flow meter model	*1
MR/MG number #09: 100 SLM	MR/MG number #10: 200 SLM	MR/MG number #11: 300 SLM	MR/MG number #12: 500 SLM	Full-scale flow rate (N ₂ conversion flow rate)	
O: Normally open C: Normally close		C: Normally close		Valve Type	
				Flow rate at fully closed control valve	
				Flow rate control range	
				Flow rate measuring range (SEF)	
±1.0% S.P. (Flow rate > 35% F.S.) ±0.35% F.S. (Flow rate ≤ 35% F.S.)		±2% S.P. (flow rate > 50% F.S.) ±1% F.S. (flow rate ≤ 50% F.S.)		Accuracy	*2
5 to 50°C (recommended temperature range: 15 to 45°C)				Operating temperature	
≤ 1 second: over full flow rate range		≤ 2 second: over full flow rate range		Response	
≤ ±0.5% F.S.		±1% F.S.		Linearity	
≤ ±0.2% F.S.		±0.5% F.S.		Repeatability	
100 to 300 kPa (d)	200 to 300 kPa (d)	150 to 350 kPa (d)	250 to 350 kPa (d)	Operating differential pressure	
≤ 300 kPa (d)		≤ 300 kPa (d)		Operating differential pressure (SEF)	
450 kPa(g)				MAX. Operating pressure	
1000 kPa(g)				Pressure resistance	
≤ 5 x 10 ⁻¹² Pa·m ³ /s (He)				Leak Integrity	
DeviceNet™ Protocol				Digital interface	
316L Stainless Steel (polished surface)				Wetted materials	
Conforming to ODVA standards, DC 24 V, 4.0 VA		Conforming to ODVA standards, DC 24 V, 4.0 VA		Power supply	
1/2 inch VCR equivalent Option: 1. 5 inch IGS		1/2 inch VCR equivalent		Standard Fitting	*3
Free				Mounting orientation	

Product specifications

EtherCAT® communication model

Mass flow controller model	*1	SEC-Z517KX	SEC-Z517MGX	SEC-Z527MGXN	SEC-Z527MGX	
Mass flow meter model	*1	SEF-Z517KX	SEF-Z517MGX	SEF-Z527MGXN	SEF-Z527MGX	
Full-scale flow rate (N ₂ conversion flow rate)		1/2 SCCM	MR/MG number #R01: 10 SCCM #R1.5: 17.5 SCCM #1.5: 55 SCCM #2.5: 175 SCCM #3.5: 550 SCCM #4.5: 1.75 SLM #5.5: 5.5 SLM	#01: 30 SCCM #02: 100 SCCM #03: 300 SCCM #04: 1 SLM #05: 3 SLM #06: 10 SLM	MR/MG number #6.5: 22 SLM #07: 30 SLM #08: 50 SLM	
Valve Type		O: Normally open C: Normally close				
Flow rate at fully closed control valve		≤ 2% F.S.				
Flow rate control range		2-100% of F.S.				
Flow rate measuring range (SEF)		0-100% of F.S.				
Accuracy	*2	±1.0% F.S.	±1.0% S.P. (Flow rate > 25% F.S.) ±0.25% F.S. (Flow rate ≤ 25% F.S.)			
Operating temperature		5 to 50°C (recommended temperature range: 15 to 45°C)				
Response		≤ 1 second: over full flow rate range				
Linearity		≤ ±0.5% F.S.				
Repeatability		≤ ±0.2% F.S.				
Operating differential pressure		50 to 300 kPa (d)	50 to 300 kPa (d) #5.5, #06: 100 to 300 kPa (d)	200 to 300 kPa (d)		
Operating differential pressure (SEF)		≤ 300 kPa (d)				
MAX. Operating pressure		450 kPa(g)				
Pressure resistance		1000 kPa(g)				
Leak Integrity		≤ 5 x 10 ⁻¹² Pa·m ³ /s (He)				
Digital interface		EtherCAT® Protocol				
Wetted materials		316L Stainless Steel (polished surface)				
Power supply		DC 24 V, 6.8 VA				
Standard Fitting	*3	1/4 inch VCR equivalent Option: 1.125 inch IGS			1/4 inch VCR equivalent Option: 1.125 inch IGS	
Mounting orientation		Free				

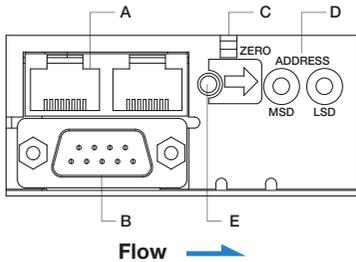
*1 The gas type and full scale settings for the SEC(SEF)-Z517MGX, Z527MGX, Z527MGXN, Z537MGX, Z547MGX, Z557MGX and Z567MGX can be changed by the operator, using special software.

*2 The precision is that associated with the full-scale MR and MG number values. The flow rate precision guaranteed temperatures conform to SEMI standards. For details, please contact HORIBA STEC.

*3 IGS: Integrated Gas System

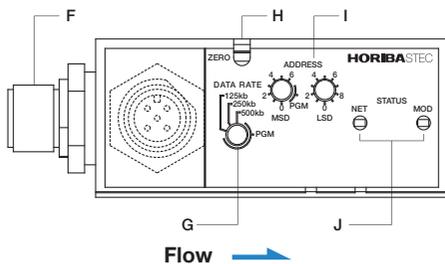
● SCCM and SLM are notations indicating the gas flow rate (mL/min, L/min, at 0°C and 101.3 kPa).

Digital/Analog communication models



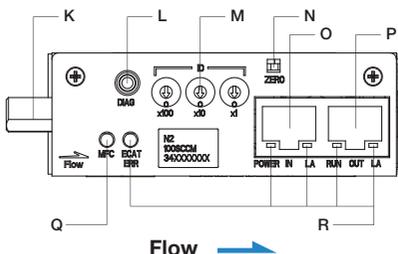
Symbol	Name	Explanation
A	Connector for digital transmission	RS-485 transmission Daisy chain available
B	Analog connector	Analog transmission and power supply
C	ZERO adjust switch	Switch for zero adjust
D	Address switch	Set from 0 x 01 to 0 x 99 (Not available from 0 x ΔA to ΔF)
E	LED indicator	Analog transmission: Green right on Digital transmission : Green right flashing * Red right on when alarming and zero offset error

DeviceNet™ communication models



Symbol	Name	Explanation
F	DeviceNet™ connector	DeviceNet™ transmission and shield type micro connector
G	Baud rate setting switch	Set baud rate
H	ZERO adjust switch	Switch for zero adjust
I	MAC ID setting switch	Set from 00 to 63
J	LED Indicator	NET :Status for network MOD :Status for node

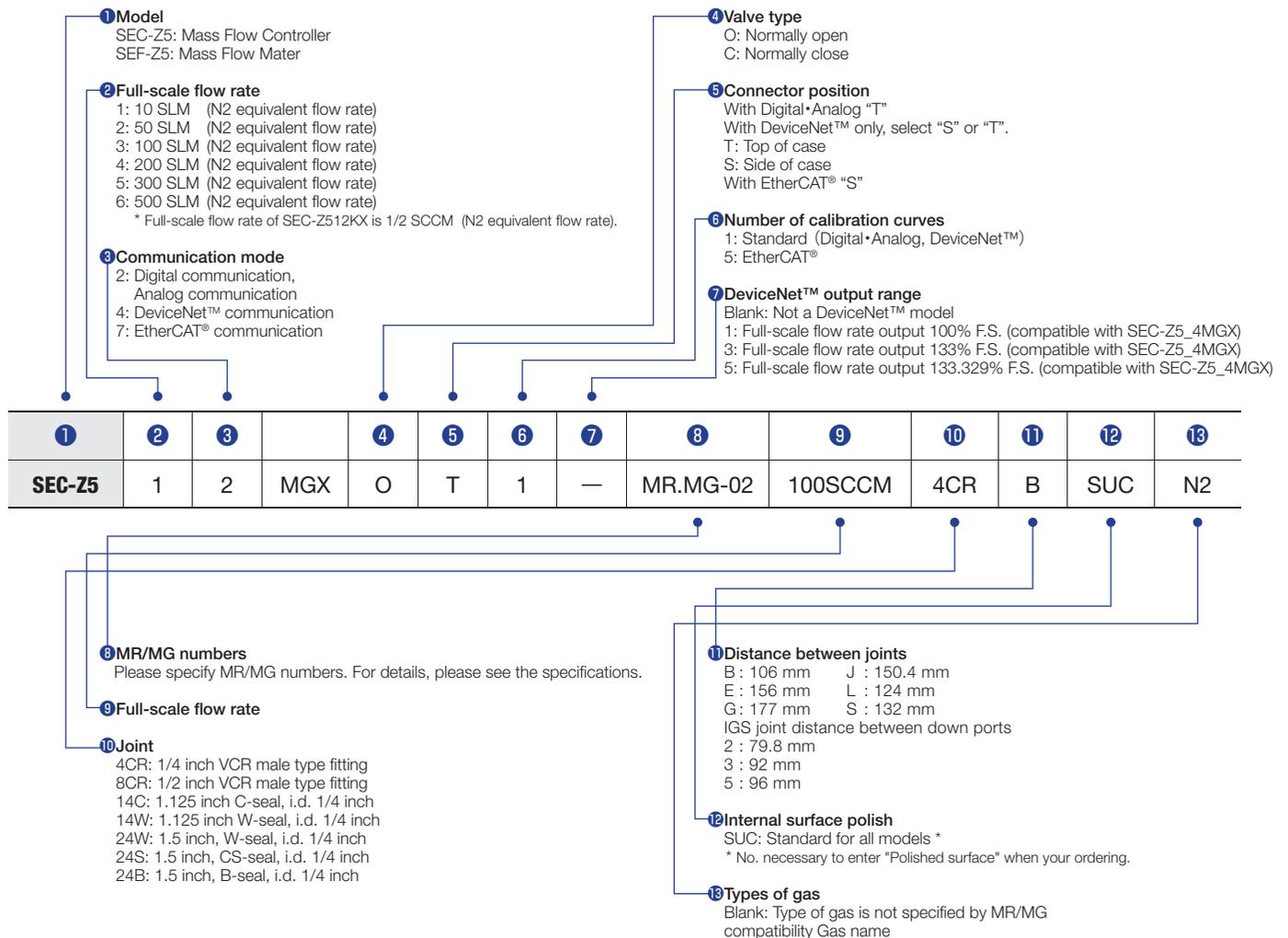
EtherCAT® communication model



Symbol	Name	Explanation
K	Power connector	Drive power supply connector
L	DIAG communication port	Service communication port
M	EtherCAT® ID selector	Settable in a range from 0x0000 to 0x0FFF * If this ID is used for EtherCAT® communication, it is required to perform a predetermined initial setting. If you have any question about how to set up, please contact us.
N	ZERO adjust switch	Zero adjust switch
O	EtherCAT® IN port	For EtherCAT® communication. Connection on IN side
P	EtherCAT® OUT port	For EtherCAT® communication. Connection on OUT side
Q	MFC indicator LED	Indicates MFC state. Normal: Turns on in green Abnormal: Turns on in red or flashes in red/green depending on abnormal cause.
R	EtherCAT® indicator LED	ECAT ERR: Indicates error state of EtherCAT® communication. POWER: Turns on in green when power is supplied. LA: Indicates link/active state of each port. RUN: Indicates state of EtherCAT® state machine.

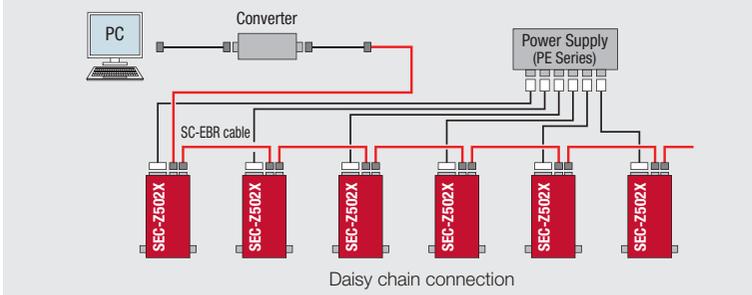
SEC-Z537MGX	SEC-Z547MGX	SEC-Z557MGX	SEC-Z567MGX	Mass flow controller model	*1
SEF-Z537MGXN	SEF-Z547MGXN	SEF-Z557MGX	SEF-Z567MGX	Mass flow meter model	*1
MR/MG number #09: 100 SLM	MR/MG number #10: 200 SLM	MR/MG number #11: 300 SLM	MR/MG number #12: 500 SLM	Full-scale flow rate (N ₂ conversion flow rate)	
O: Normally open C: Normally close		C: Normally close		Valve Type	
				Flow rate at fully closed control valve	
≤ 2% F.S.				Flow rate control range	
2-100% of F.S.				Flow rate measuring range (SEF)	
0-100% of F.S.				Accuracy	*2
±1.0% S.P. (Flow rate > 35% F.S.) ±0.35% F.S. (Flow rate ≤ 35% F.S.)		±2% S.P. (flow rate > 50% F.S.) ±1% F.S. (flow rate ≤ 50% F.S.)		Operating temperature	
5 to 50°C (recommended temperature range: 15 to 45°C)				Response	
≤ 1 second: over full flow rate range		≤ 2 second: over full flow rate range		Linearity	
≤ ±0.5% F.S.		±1% F.S.		Repeatability	
≤ ±0.2% F.S.		±0.5% F.S.		Operating differential pressure	
100 to 300 kPa (d)	200 to 300 kPa (d)	150 to 350 kPa (d)	250 to 350 kPa (d)	Operating differential pressure (SEF)	
≤ 300 kPa (d)		≤ 300 kPa (d)		MAX. Operating pressure	
450 kPa(g)				Pressure resistance	
1000 kPa(g)				Leak Integrity	
≤ 5 x 10 ⁻¹² Pa·m ³ /s (He)				Digital interface	
EtherCAT [®] Protocol				Wetted materials	
316L Stainless Steel (polished surface)				Power supply	
DC 24 V, 6.8 VA				Standard Fitting	*3
1/2 inch VCR equivalent Option: 1.5 inch IGS			1/2 inch VCR equivalent	Mounting orientation	
Free					

▶ Selecting a model



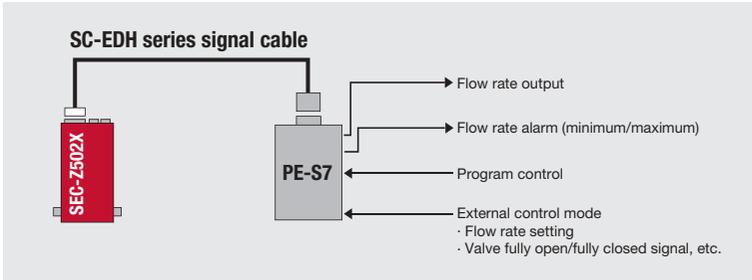
Connector examples

Digital communication

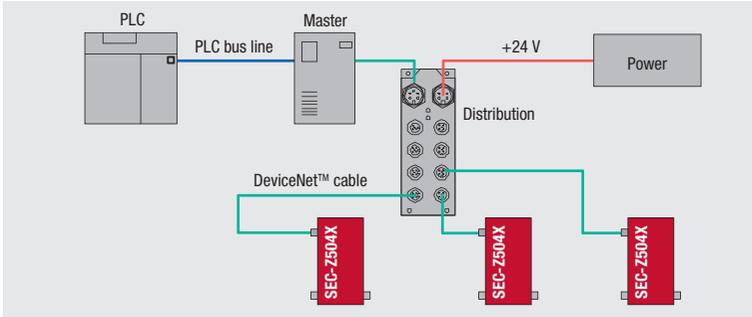


Analog communication

Using PE-S7 control unit



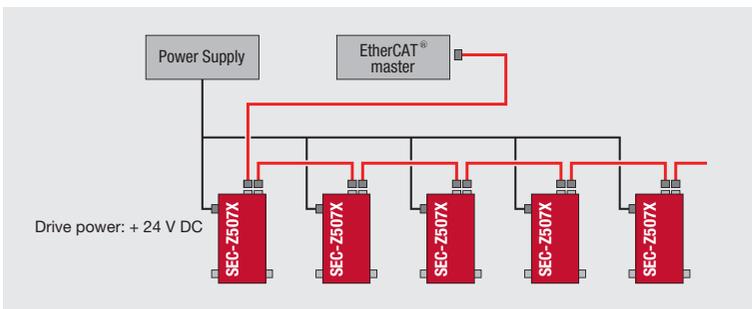
DeviceNet™ communication



DeviceNet™ communications

DeviceNet™ is an open and global field network that was developed by the ODVA (Open DeviceNet™ Vendor Association, Inc.) as a unique means for supporting standardization worldwide. The ODVA offers EDS (Electronic Data Sheet) specifications, which are designed to allow shared operability and programming in a multi-vendor environment. The ODVA also carries out conformance testing. Devices that have passed the ODVA's conformance testing can display the logo.

EtherCAT® communication



What is EtherCAT® communication?

Open field bus system based on Ethernet. ETG (EtherCAT® Technology Group) has been established as an international forum to promote support and diffusion of EtherCAT®, and maintain mutual compatibility. ETG specifies functional requirements, conformance tests and its certification procedure, and permits only devices which satisfy conditions specified by ETG to use the EtherCAT logo.

RS485 digital communication connector

Pin No.	Signal name
1	Signal ground [D. COM]
2	Signal ground [D. COM]
3	N.C.
4	Serial output/input (-)
5	Serial output/input (+)
6	N.C.
7	N.C.
8	N.C.

Connector used: RJ-45

Analog connectors

Pin No.	Signal name
1	Valve open/closed input *1
2	Flow rate output signal: 0 to 5 V DC
3	Power source: +15 V DC
4	Power source: Common *2
5	Power source: -15 V DC
6	Flow rate setting signal: 0 to 5 V DC
7	Signal: Common *2
8	Signal: Common *2
9	NC

Connector used: D-subminiature 9-contact-pin connector (with M3 fastening screws)

*1 SEF series is N.C.

*2 The pin No. 4 Common power source and pin No. 7 Common signal are not connected within the mass flow controller. The pin No. 7 and No. 8 Common signals are connected within the mass flow controller.

DeviceNet™ communication connectors

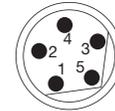


Pin No.	Signal name
1	Drain
2	V+
3	V-
4	CAN_H
5	CAN_L

Advantages

- Reduces costs, since AD/DA converters and I/O boards are not required.
- The user simply connects the devices through network cables and makes address settings. This reduces both the number of processes required and the time involved.
- No special accessories are necessary for the devices. Users can simply choose DeviceNet™ conforming products, which reduces costs.

Power connector



Pin No.	Signal name
1	V+
2	N.C.
3	Power Common
4	N.C.
5	N.C.

Connector used: M8 5pin male connector

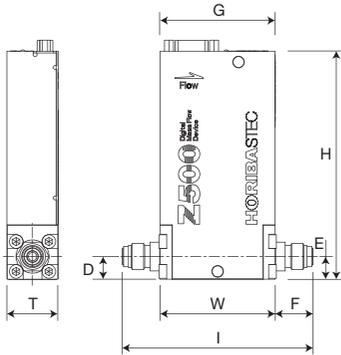
* Use connectors that conform to the EtherCAT® Technology Group standard: ETG5003.2020.

Features

- High bus efficiency and high-speed data scan is realized by simultaneously communicating with many devices.
- The master can use the standard Ethernet interface when connecting to devices, and does not require expensive dedicated hardware.

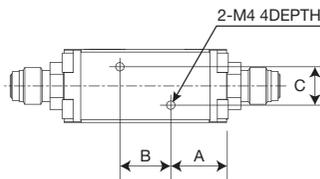
Dimensions

▶ VCR male type

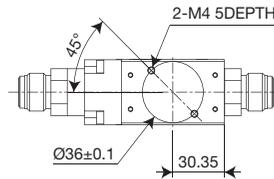


Model	Size	Fittings	H	T	W	I	A	B	C	D	E	F	G	
SEC(SEF)-Z512KX	1/4inch	4CRB	126±1	28.5±0.5	63.8	106±1	21.9	20±1	15±0.1	12.7	12.7	21.1	63.8	
SEC(SEF)-Z512(MG)X		4CRL				124±1								
SEC(SEF)-Z522(MG)XN		4CRE				156±1								
SEC(SEF)-Z532MGX(N)	1/2inch	8CRS	139±1	38.3±0.5	70.4	Please refer to the bottom view.				18.5	18.5	29	63.8	
SEC(SEF)-Z542MGX(N)		8CRJ			150.4±1									
SEC(SEF)-Z552MGX		8CRG	148.5±1	49±0.5	(92.4)					132±1	22	22	29	78
		8CRJ								150.4±1				
SEC(SEF)-Z562MGX	8CRG				177±1									
SEC(SEF)-Z514KX	1/4inch	4CRB	126±1	28.5±0.5	63.8	106±1	21.9	20±1	15±0.1	12.7	12.7	21.1	63.8	
SEC(SEF)-Z514MGX		4CRL				124±1								
SEC(SEF)-Z524MGXN		4CRE				156±1								
SEC(SEF)-Z534MGX(N)	1/2inch	8CRS	150±1	38.3±0.5	70.4	Please refer to the bottom view.				18.5	18.5	29	63.8	
SEC(SEF)-Z544MGX(N)		8CRJ			150.4±1									
SEC(SEF)-Z554MGX		8CRG	158.5±1	49±0.5	92.4					132±1	22	22	29	78
		8CRJ								150.4±1				
SEC(SEF)-Z564MGX	8CRG				177±1									
SEC(SEF)-Z517KX	1/4inch	4CRL	126±1	28.5±0.5	81.8	124±1	21.9	20±1	15±0.1	12.7	12.7	21.1	81.8	
SEC(SEF)-Z517MGX														
SEC(SEF)-Z527MGXN														
SEC(SEF)-Z537MGX(N)	1/2inch	8CRS	145±1	38.3±0.5	70.4	Please refer to the bottom view.				18.5	18.5	29	81.3	
SEC(SEF)-Z547MGX(N)		8CRJ			150.4±1									
SEC(SEF)-Z557MGX		8CRG	159.3±1	49±0.5	92.4					132±1	22	22	29	85.5
		8CRJ								150.4±1				
SEC(SEF)-Z567MGX	8CRG				177±1									

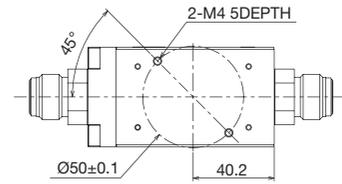
Bottom view



SEC(SEF)-Z51_KX/Z51_(MG)N/Z52_(MG)XN

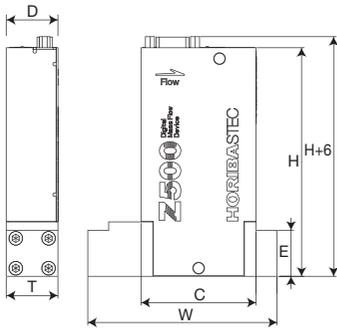


SEC(SEF)-Z53_MGX(N)/Z54_MGX(N)

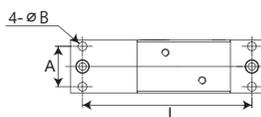


SEC(SEF)-Z55_MGX/Z56_MGX

▶ Surface mount type



Bottom view



Model	Size	Fittings	H	T	W	I	A	B	C	D	E
SEC(SEF)-Z512KX	1.125inch	C-seal 14C3	126±1	28.5±0.2	93±0.5	79.8±0.25	21.8±0.2	4.75±0.12 *1	(63.8)	(28.5)	25.4±0.5
SEC(SEF)-Z512(MG)X		W-seal 14W2	126±1	28.5±0.2	93±0.5	79.8±0.25	21.8±0.2	4.4±0.1	(63.8)	(28.5)	25.4±0.5
SEC(SEF)-Z522(MG)XN		14W3			105±0.5	92±0.2					
SEC(SEF)-Z512KX	1.5inch	CS-seal 24S2	126±1	37.6	93±0.5	79.8±0.25	30±0.1	5.5	(63.8)	(28.5)	26
SEC(SEF)-Z512(MG)X				130±1	38.6					(38.6)	32.5
SEC(SEF)-Z512KX	1.5inch	W-seal 24W2	130±1	39	93±0.5	79.8±0.25	30±0.1	5.5	(63.8)	(28.5)	37
SEC(SEF)-Z512(MG)X										(38.6)	
SEC(SEF)-Z522(MG)X											37
SEC(SEF)-Z514KX	1.5inch	C-seal 26C3	139±1	38.3±0.5	107±1	92±0.3	30.2	5.2	(63.8)	(38.3)	31.2
SEC(SEF)-Z532MGX(N)		W-seal 26W3	139±1	39±0.3	109±1	92±0.3	28±0.3	6.5	(63.8)	(38.3)	37
SEC(SEF)-Z542MGX(N)	1.5inch	C-seal 14C3	126±1	28.5±0.2	93±0.5	79.8±0.25	21.8±0.2	4.75±0.12 *2	(63.8)	(28.5)	25.4±0.5
SEC(SEF)-Z514KX	1.125inch	W-seal 14W2	126±1	28.5±0.2	93±0.5	79.8±0.25	21.8±0.2	4.4±0.1	(63.8)	(28.5)	25.4±0.5
SEC(SEF)-Z514MGX		14W3			105±0.5	92±0.2					
SEC(SEF)-Z524MGXN											
SEC(SEF)-Z514KX	1.5inch	CS-seal 24S2	126±1	37.6	93±0.5	79.8±0.25	30±0.1	5.5	(63.8)	(28.5)	26
SEC(SEF)-Z514MGX				130±1	38.6					(38.6)	32.5
SEC(SEF)-Z524MGX											
SEC(SEF)-Z514KX	1.5inch	W-seal 24W2	130±1	39	93±0.5	79.8±0.25	30±0.1	5.5	(63.8)	(28.5)	37
SEC(SEF)-Z514MGX										(38.6)	
SEC(SEF)-Z524MGX											37
SEC(SEF)-Z534MGX(N)	1.5inch	C-seal 26C3	150±1	38.3±0.5	107±1	92±0.3	30.2	5.2	(63.8)	(38.3)	31.2
SEC(SEF)-Z544MGX(N)		W-seal 26W3	150±1	39±0.3	109±1	92±0.3	28±0.3	6.5	(63.8)	(38.3)	37
SEC(SEF)-Z517KX	1.125inch	C-seal 14C3	126±1	28.5±0.2	93±0.5	79.8±0.25	21.8±0.2	4.75±0.12 *3	(63.8)	(28.5)	25.4±0.5
SEC(SEF)-Z517MGX		W-seal 14W2	126±1	28.5±0.2	93±0.5	79.8±0.25	21.8±0.2	4.4±0.1	(63.8)	(28.5)	25.4±0.5
SEC(SEF)-Z527MGXN		14W3			105±0.5	92±0.2					
SEC(SEF)-Z517KX	1.5inch	CS-seal 24S2	126±1	37.6	93±0.5	79.8±0.25	30±0.1	5.5	(63.8)	(28.5)	26
SEC(SEF)-Z517MGX				130±1	38.6					(38.6)	32.5
SEC(SEF)-Z517KX	1.5inch	W-seal 24W2	130±1	39	93±0.5	79.8±0.25	30±0.1	5.5	(63.8)	(28.5)	37
SEC(SEF)-Z517MGX										(38.6)	
SEC(SEF)-Z527MGX											

*1:SEC(SEF)-Z522(MG)XN 4.4±0.1

*2:SEC(SEF)-Z524MGXN 4.4±0.1

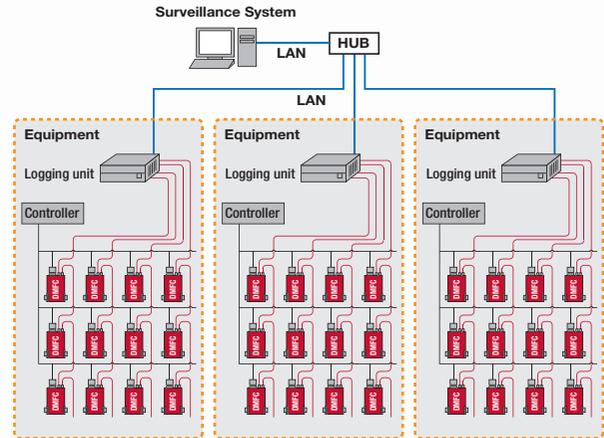
*3:SEC(SEF)-Z527MGXN 4.4±0.1

Please contact HORIBA other than above table.

► eDiagnostic digital mass flow controller monitoring system

The importance of preventative maintenance for production equipment in semiconductor device manufacturing plants is widely acknowledged. In fact, preventative maintenance is considered a critical factor for increasing productivity. HORIBA STEC offers a preventative maintenance system for its mass flow controllers, which are considered key devices in the semiconductor manufacturing process. The mass flow controller's preventative maintenance system monitors the flow rate control conditions and the position of the valve, and determines the status of overall flow rate control in the mass flow controller. The system informs the user of what sort of maintenance is required before the mass flow controller becomes unable to control the flow rate. It is considered difficult to predict the maintenance required for a mass flow controller's functioning by monitoring its flow control status alone. HORIBA STEC's mass flow controller monitoring system collects information on the control status of the digital mass flow controllers (analog control) in semiconductor manufacturing equipment using digital communications, and monitors whether or not there is a need for any preventative maintenance. This system is compatible with LAN (TCP/IP) networks, and a single superior Surveillance Server can be used to monitor the mass flow controllers in each semiconductor manufacturing system. It's also relatively easy to create a wide area network for this monitoring system. The logging unit can be used to log the flow rate control status of digital mass flow controller in each semiconductor manufacturing system. The Surveillance Server is connected to the logging unit through a LAN. The logging unit monitors the flow rate control conditions and the position of the flow control valve, and determines whether any preventative maintenance is necessary. This data can be used to investigate the reasons for problems or to review changes in the gas pressure, in addition to determining whether or not preventative maintenance is required.

► Sample system setup



► Digital mass flow controller monitoring software; compatible with RS-485 and DeviceNet™ communication

HORIBA STEC also offers monitoring software that is compatible with HORIBA STEC's digital mass flow controller protocol (F-Net protocol) and is able to monitor all mass flow controller related transmissions. This software makes it easy to check the status of transmissions between control units such as the PLC or PC and the SEC-Z500X series units. In addition to checking if the digital transmission cable and signal converter are installed correctly, it can use the digital mass flow controller's address transmissions to monitor and control installation information and valve operating status. When DeviceNet™ transmission is used, the software operates using digital transmission information only. In fact, with DeviceNet™, it is possible to monitor the control status of the digital mass flow controller using just this software, a PC, and the DeviceNet™ transmission unit; there is no need for a special, additional control unit mounted on the equipment.

► Easy-to-use digital mass flow controller monitoring software

The digital mass flow controller monitoring system uses eDiagnostic monitoring software. The mass flow controller's control status is monitored through digital transmissions, and then logged and saved in a PC. The eDiagnostic software also features a function that outputs alarms as necessary based on the monitored flow rate control status and valve aperture information. Real-time monitoring makes it possible to go back and review the circumstances surrounding changes in the control status and gas supply conditions. The monitoring information is also extremely useful in investigating the causes of any malfunctions that arise.

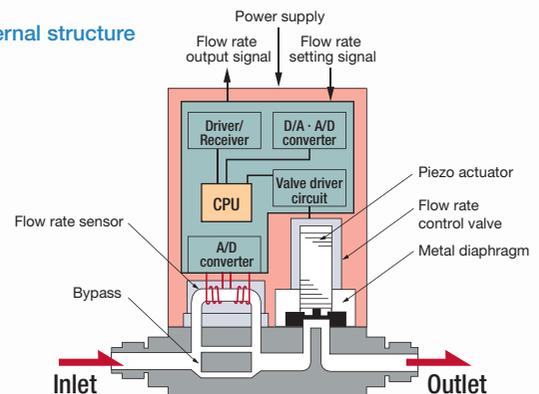
► Digital mass flow controller control software

HORIBA STEC also offers control software that is compatible with HORIBA STEC's digital mass flow controller protocol (F-Net protocol). In addition to offering digital mass flow controller flow rate control (step control, loop control functions, etc.), it is also designed to output the aperture control signal for valves mounted on the same gas line. Thanks to these features, this software offers optimal small-scale gas supply system control.

► Structure and operating principles

The general structure of the SEC-Z500X series of mass flow controllers is shown in the diagram to the right. These mass flow controllers have a flow rate measurement section that includes a sensor, bypass, flow rate control valve, and special circuitry. A CPU is part of the circuitry, which makes it both multi-functional and highly efficient. The gas is input from an Inlet joint, and is divided so that it flows over both the flow rate sensor and a bypass. The sensor measures the mass flow rate of the gas, and the flow rate control valve modifies the flow rate so that the difference between the measured flow rate and the flow rate received from the external flow rate setting signal is 0 (zero). The units feature a loop circuit, so even if there is a secondary pressure change or ambient temperature change that could affect the supply pressure of the introduced gas, the flow rate is instantaneously corrected, which ensures stable flow rate control.

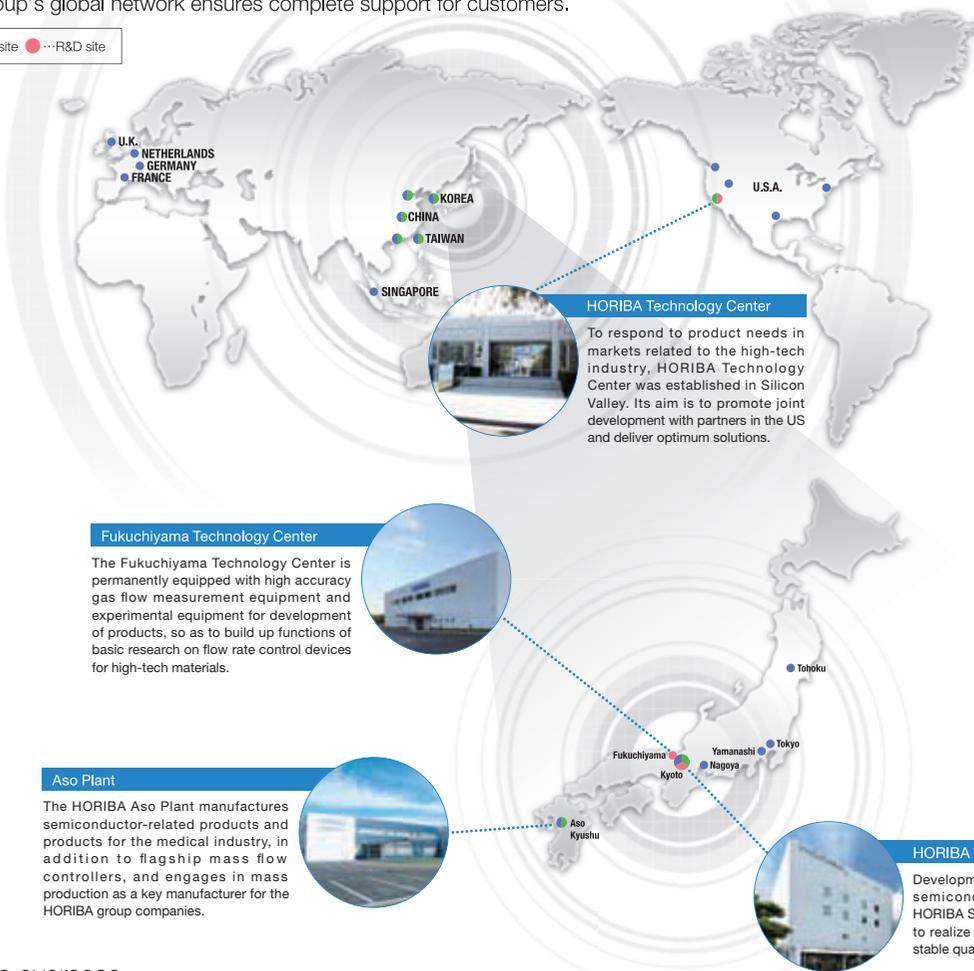
► Internal structure



Global support

The HORIBA Group's global network ensures complete support for customers.

● Sales office ● Production site ● R&D site



Fukuchiyama Technology Center

The Fukuchiyama Technology Center is permanently equipped with high accuracy gas flow measurement equipment and experimental equipment for development of products, so as to build up functions of basic research on flow rate control devices for high-tech materials.

Aso Plant

The HORIBA Aso Plant manufactures semiconductor-related products and products for the medical industry, in addition to flagship mass flow controllers, and engages in mass production as a key manufacturer for the HORIBA group companies.

HORIBA Technology Center

To respond to product needs in markets related to the high-tech industry, HORIBA Technology Center was established in Silicon Valley. Its aim is to promote joint development with partners in the US and deliver optimum solutions.

HORIBA Advanced Technology Center

Development and manufacture of HORIBA, Ltd. semiconductor sensors are integrated with HORIBA STEC, Co., Ltd. fluid control technologies to realize speedy development, downsizing, and stable quality of products.

Principal branches overseas

U.S.A

HORIBA Instruments Incorporated Sunnyvale Head Office (Technology Center)

430 Indio Way, Sunnyvale California 94085
PHONE: (1)408-730-4772 FAX: (1)408-730-8975

Austin Office

9701 Dessau Road, Suite 605 Austin Texas 78754
PHONE: (1)512-836-9560 FAX: (1)512-836-8054

Portland Office

10110 SW. Nimbus Avenue, Suite B11 Portland Oregon 97223
PHONE: (1)503-624-9767 FAX: (1)503-968-3236

Reno Office (R&D Center)

605 Spice Island Drive, #5 Sparks, Nevada 89431
PHONE: (1)775-358-2332 FAX: (1)775-358-0434

Albany Office

Suite104, 58 Clifton Country Rd, Clifton Park New York 12065
PHONE: (1)518-331-1371

SINGAPORE

HORIBA INSTRUMENTS (SINGAPORE) Pte. Ltd.

3 Changi Business Park Vista #01-01 Akzonobel House,
486051 Singapore
PHONE: (65)6-745-8300 FAX: (65)6-745-8155

KOREA

HORIBA STEC Korea, Ltd.

110, Suntechcity, 474, Dunchon-daero
Jungwon-gu, Seongnam-si, Gyeonggi-do,13229, Korea
PHONE: (82)31-777-2277 FAX: (82)31-777-2288

TAIWAN

HORIBA Taiwan, Inc

3F, No.18, Lane 676, Zhonghua Rd., Zhubei City, Hsinchu
Country 302, Taiwan
PHONE: (886)3-656-1160 FAX: (886)3-656-8231

Tainan Office

1F, No.117, Chenggong Rd., Shanhua Dist., Tainan City
741, Taiwan
PHONE: (886)3-583-4592 FAX: (886)6-583-2409

CHINA

HORIBA (China) Trading Co., Ltd.

Beijing office

12F, Metropolis Tower (XinDongFang South Tower),
No.2, HaidianDong 3 Street, Haidian District, Beijing, China
PHONE: (86) 10 85679966 FAX: (86) 10 85679066

Shanghai office

Unit D, 1F, Building A, Synnex International Park, 1068 West
Tianshan Road, Shanghai, China
PHONE: (86) 21 62896060 FAX: (86) 21 62895553

Shanghai service center

Room 303, No.84, Lane887, Zu-chong-zhi Rd., Zhangjiang,
Hi-tech, Shanghai, China
PHONE: (86) 21 51317150 FAX: (86) 21 51317660

Chengdu office

Room C1, 17F, No.86, City Center People South Yiduan,
Qingyang Section, Chengdu, China
PHONE: (86) 18583234999

Xi'an office

Room 411, Building A, South Fenghui Road, No 36,
Xiangshu Street, Xi'an, China
PHONE: (86) 029 88868480 FAX: (86) 029 88868481

Shenzhen office

Room 3E, Unit3, Building5, Youpinjianzhu Estate,
Longhua District, Shenzhen, China
PHONE: (86) 13602530661

UK

HORIBA UK Ltd. Northampton office

Kyoto Close, Moulton Park, Northampton, NN3 6FL,
England
PHONE: (44) 1604 542600 FAX: (44) 1604 542696

FRANCE

HORIBA UK Ltd. Grenoble office

2B avenue de vignate 38610 Gieres France
PHONE: (33) 4 76 42 07 58

THE NETHERLANDS

HORIBA UK Ltd. Nijmegen office

PHONE: (31) 24 301 0235

GERMANY

HORIBA Europe GmbH

Hugo-Junckers-Ring 1 01109 Dresden Germany
PHONE: (49) 351/889 68 07

Principal branches in Japan

Head Office

11-5, Hokodate-cho, Kamitoba, Minami-ku, Kyoto-shi,
Kyoto, 601-8116, Japan
PHONE: (81)75-693-2300 (Representative) FAX: (81)75-693-2350

Aso Factory

Torikokogyodanchi, 358-11, Koumaibata, Toriko,
Nishiharamura, Aso-gun, Kumamoto, 861-2401, Japan
PHONE: (81)96-279-2921 FAX: (81)96-279-3364

Tohoku Sales Office

4-21-8, Izumichuo, Izumi-ku, Sendai-shi, Miyagi, 981-3133, Japan
PHONE: (81)22-772-6717 FAX: (81)22-772-6727

Tokyo Sales Office

3F KandaAwaji-cho 2-chome Building, 2-6, KandaAwaji-cho,
Chiyoda-ku, Tokyo, 101-0063, Japan
PHONE: (81)3-6206-4731 FAX: (81)3-6206-4740

Yamanashi Sales Office

2-14-13, Marunouchi, Kofu-shi, Yamanashi, 400-0031, Japan
PHONE: (81)55-231-1351 FAX: (81)55-231-1352

Nagoya Sales Office

6F Chikusa 2nd Building, 3-15-31, Aoi,
Higashi-ku, Nagoya-shi, Aichi, 461-0004, Japan
PHONE: (81)52-936-9511 FAX: (81)52-936-9512

Kyushu Sales Office

Torikokogyodanchi, 358-11, Koumaibata, Toriko,
Nishiharamura, Aso-gun, Kumamoto, 861-2401, Japan
PHONE: (81)96-279-2922 FAX: (81)96-279-3364

Fukuchiyama Technology Center

Miwa, 11-1, Miwamachi, Fukuchiyama-shi,
Kyoto, 620-1445, Japan
PHONE: (81)773-59-2070 FAX: (81)773-59-2074

High Performance Mass Flow Controller

SEC-Z500X

<http://www.secz500.com>

IMS

The HORIBA Group adopts IMS (Integrated Management System) which integrates Quality Management System ISO9001, Environmental Management System ISO14001, and Occupational Health and Safety Management System OHSAS18001. We have now integrated Business Continuity Management System ISO22301 in order to provide our products and services in a stable manner, even in emergencies.



Applying to the EU RoHS Directive : This products is compliant with the restriction of the designated 6 hazardous substances(*).
(*) lead, cadmium, mercury, hexavalent chromium, polybrominated biphenyls (PBB) and polybrominated diphenyl ethers (PBDE)

Using lead-free soldering : Lead-free soldering is used for mounting components of printed circuit boards.

- Many countries consider the reinforcement of regulations concerning the risk caused by lead to human body and the environment

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HORIBASTECH

HORIBA STEC, Co., Ltd.

<http://www.horiba.com/horiba-stec>



Please read the operation manual before using this product to ensure safe and proper handling of the product.

HEAD OFFICE

11-5, Hokodate-cho, Kamitoba, Minami-ku, Kyoto, 601-8116 Japan
PHONE: (81)75-693-2312 FAX: (81)75-693-2331

U.S.A.
HORIBA Instruments Incorporated
Sunnyvale Head Office (Technology Center)
Austin Office
Portland Office
Reno Office
Albany Office

SINGAPORE
HORIBA Instruments (Singapore) Pte Ltd.
KOREA
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